

	ATTY DOCKET NO. P-US058-A-MF	APPLICATION NO. 10/763,594
	APPLICANT(S) Hai Hong	
	FILING DATE January 22, 2004	GROUP ART UNIT 1732

### U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
JW	3,598,467	08/10/1971	Durk Jon Pearson	350	3.5	
JW	3,600,249	08/17/1971	Jackson, et al.	156	197	
JW	3,697,630	10/10/1972	Stanley Y. Yoshino	264	28	
JW	5,190,637	03/02/1993	Henry Guckel	205	118	
JW	5,580,699	12/03/1996	Layman, et al.	430	311	
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JW	6,027,630	02/22/2000	Adam L. Cohen	205	135	
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JW	6,378,273	04/30/2002	Trani, et al.	53	450	
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*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
JW	2002/0100256	08/01/2002	Trani, et al.	53	452	

### OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

JW		Cohen, et al., "EFAB: Batch Production of Functional, Fully-Dense Metal Parts with Micron-Scale Features", Proc. 9th Solid Freeform Fabrication, The University of Texas at Austin, August 1998, pg. 161.
JW		Adam L. Cohen, et al., "EFAB: Rapid, Low-Cost Desktop Micromachining of High Aspect Ratio True 3-D MEMS", Proc. 12th IEEE Micro Electro Mechanical Systems Workshop, IEEE, Jan 1999, pg. 244.
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JW		Adam L. Cohen, "3-D Micromachining by Electrochemical Fabrication", Micromachine Devices, March 1999, pgs. 6-7.
JW		Gang Zhang, et al., "EFAB: Rapid Desktop Manufacturing of True 3-D Microstructures", Proc. 2nd International Conference on Integrated MicroNanotechnology for Space Applications, The Aerospace Co., April 1999.
JW		F. Tseng, et al., "EFAB: High Aspect Ratio, Arbitrary 3-D Metal Microstructures Using a Low-Cost Automated Batch Process", 3rd International Workshop on High Aspect Ratio Microstructure Technology (HARMST'99), June 1999.
JW		Adam L. Cohen, et al., "EFAB: Low-Cost, Automated Electrochemical Batch Fabrication of Arbitrary 3-D Microstructures", Micromachining and Microfabrication Process Technology, SPIE 1999 Symposium on Micromachining and Microfabrication, September 1999.

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INFORMATION DISCLOSURE CITATION	ATTY DOCKET NO. P-US058-A-MF	APPLICATION NO. 10/763,594
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)		
JW		F. Tseng, et al., "EFAB: High Aspect Ratio, Arbitrary 3-D Metal Microstructures Using a Low-Cost Automated Batch Process", MEMS Symposium, ASME 1999 International Mechanical Engineering Congress and Exposition, November, 1999.
JW		Adam L. Cohen, "Electrochemical Fabrication (EFABTM)", Chapter 19 of the MEMS Handbook, edited by Mohamed Gad-El-Hak, CRC Press, 2002, pgs. 19/1 - 19/23.

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